

<b>FORM PTO-1449</b>  <b>INFORMATION DISCLOSURE CITATION IN AN APPLICATION</b>  <i>(Use several sheets if necessary)</i>	<b>Docket Number (Optional)</b> 81872.0124	<b>Application Number</b> 10/597,514
<b>Applicant</b> Youhei SAKAI, et al.		
<b>Filing Date</b> July 27, 2006		<b>Group Art Unit</b> 1725

## **U.S. PATENT DOCUMENTS**

## **FOREIGN PATENT DOCUMENTS**

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

**OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)**

Takeshi SAITO, et al. "A New Directional Solidification Technique for Polycrystalline Solar Grade Silicon"  
15<sup>th</sup> Photovoltaic Specialist Conference 1981, pp. 576-580

<b>EXAMINER</b> /Seyed Masoud Malekzadeh/	<b>DATE CONSIDERED</b> 03/03/2009
--	--------------------------------------

**EXAMINER:** Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.